

# pn – diodes

# Schottky diodes

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# Exam

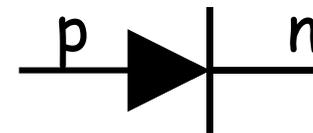
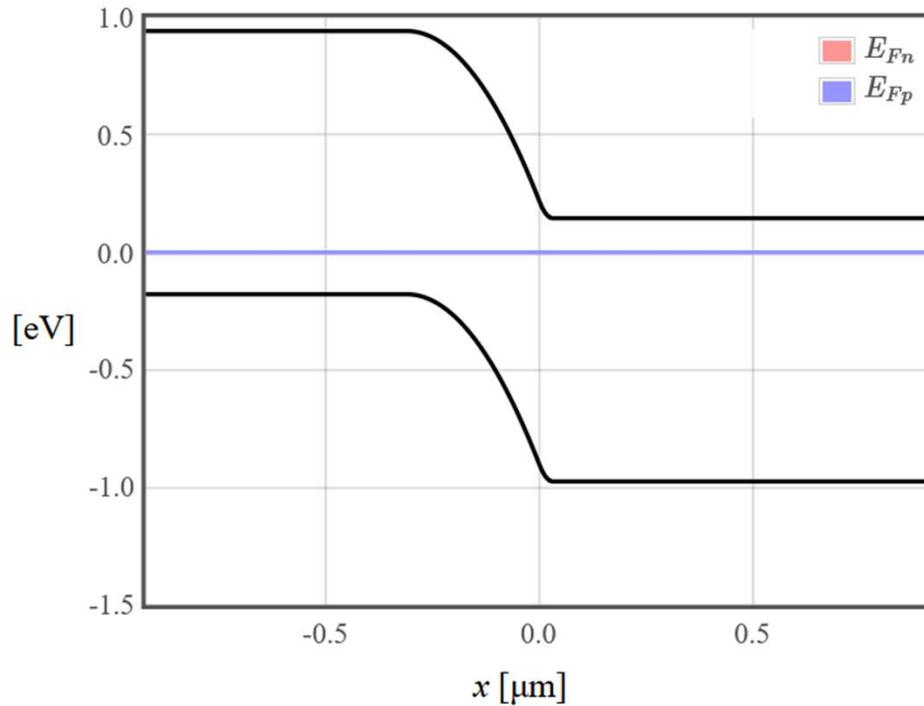
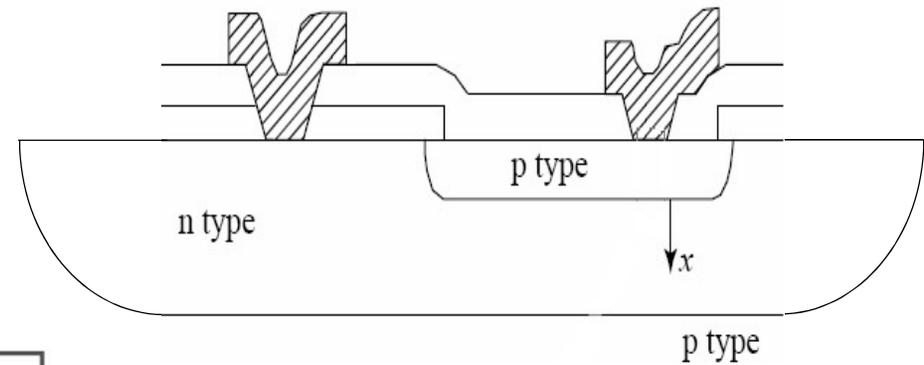
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The exam on 22.11.2024 is not for students taking the course this year.

The exam is at the end of the semester

14:00 29.01.2025 P2

# pn junctions



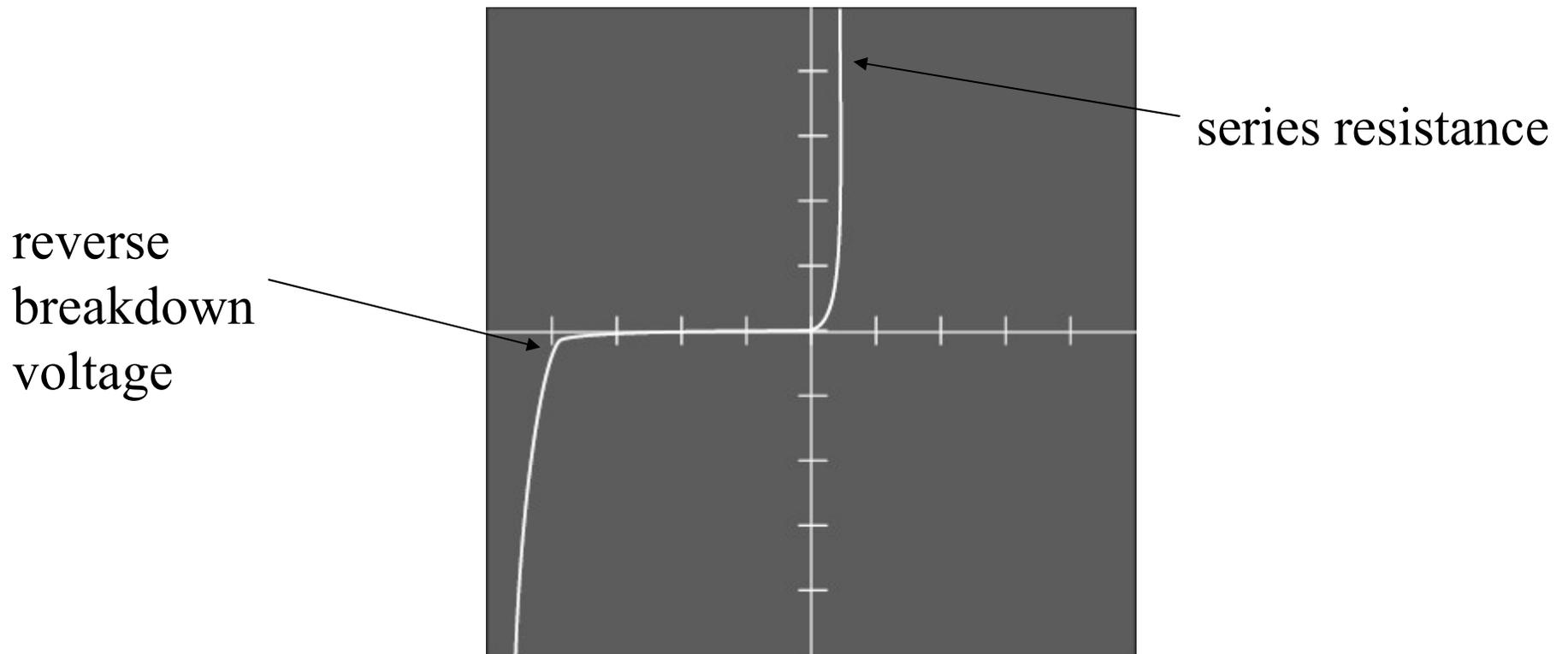
# Real diodes

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$$I = I_s \left( \exp\left(\frac{eV}{nk_B T}\right) - 1 \right)$$

$n$  = nonideality factor

$n = 1$  for an ideal diode



# Real diodes

There is constant generation/recombination of electron hole pairs.

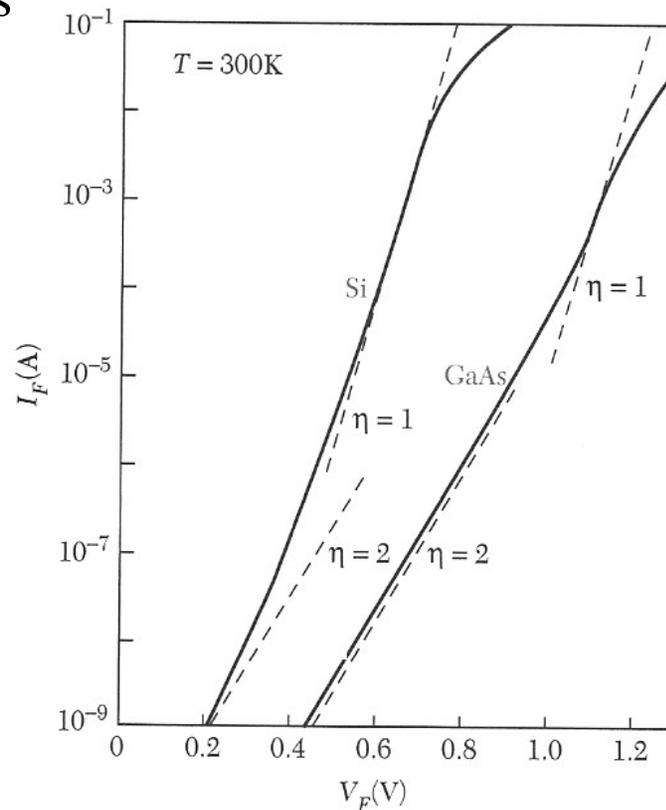
$$I = I_s \left( \exp \left( \frac{eV}{nk_B T} \right) - 1 \right)$$

$$I = I_{s1} \left( \exp \left( \frac{eV}{k_B T} \right) - 1 \right) + I_{s2} \left( \exp \left( \frac{eV}{2k_B T} \right) - 1 \right)$$

In forward bias there is less current due to recombination.

In reverse bias there is an extra current from generation.

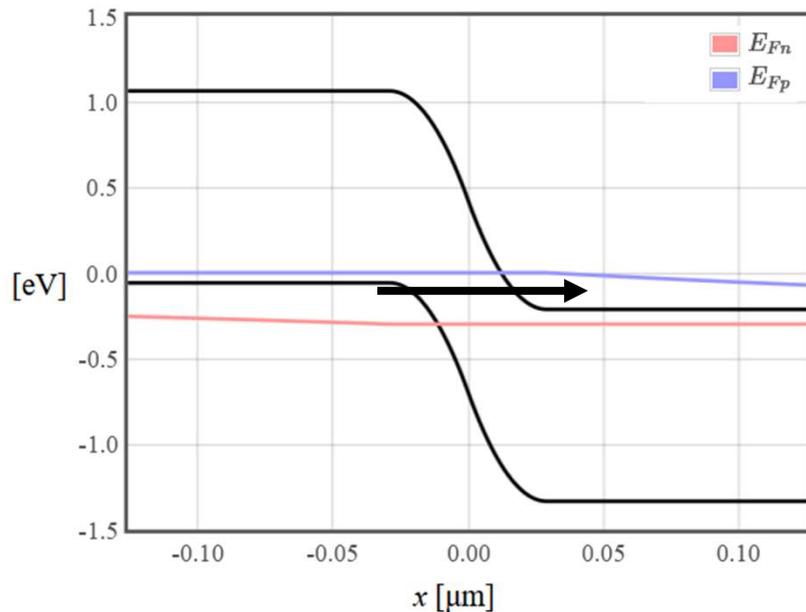
Low bias:  
recombination  
dominates,  $n = 2$



Very high bias: series resistance

High bias: ideal behavior,  $n = 1$

# Zener tunneling



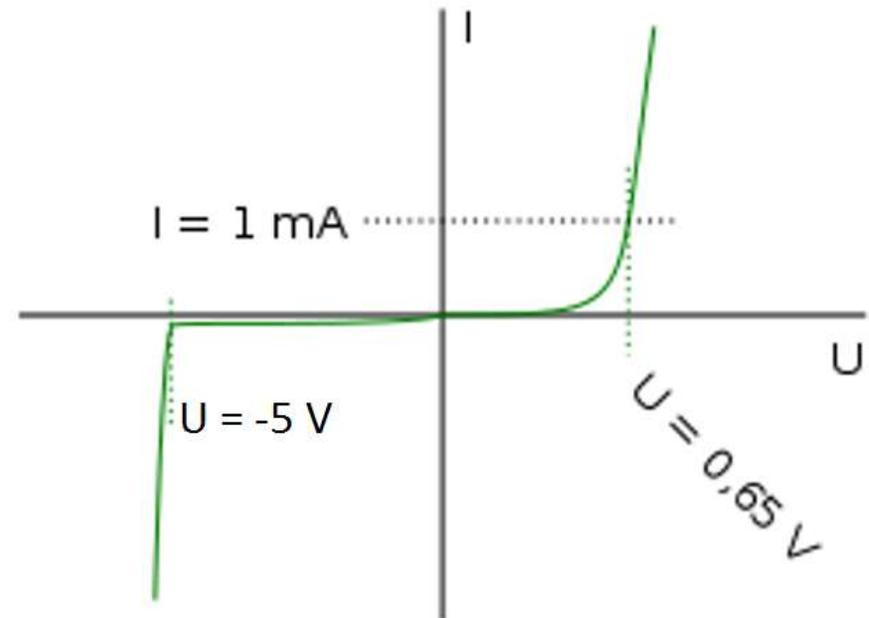
Electrons tunnel from valence band to conduction band

Occurs at high doping

$$|V_{\text{zener}}| < 5.6 \text{ V}$$



(Zener diode)

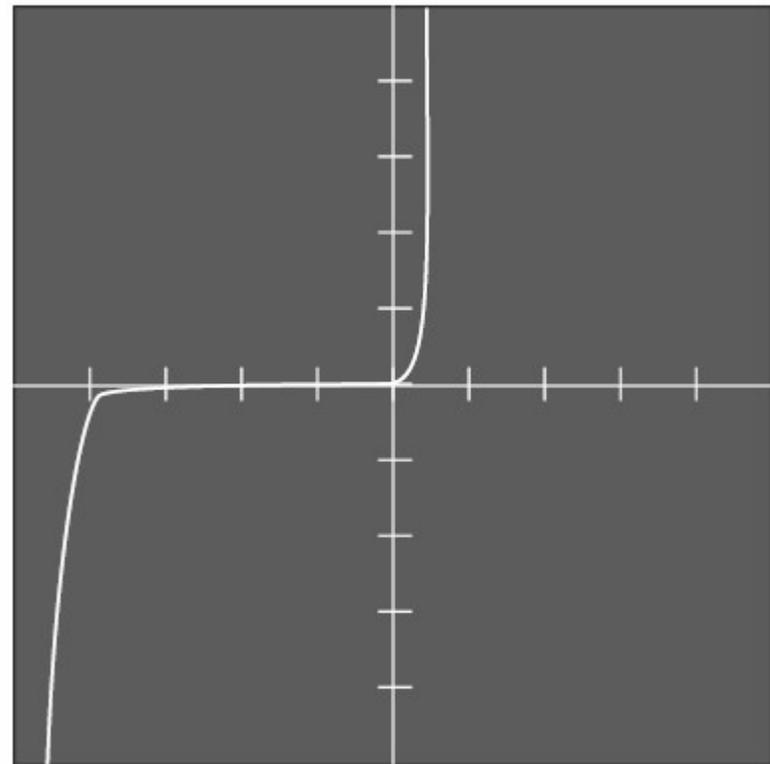


# Avalanche breakdown

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Impact ionization  
causes an avalanche of  
current

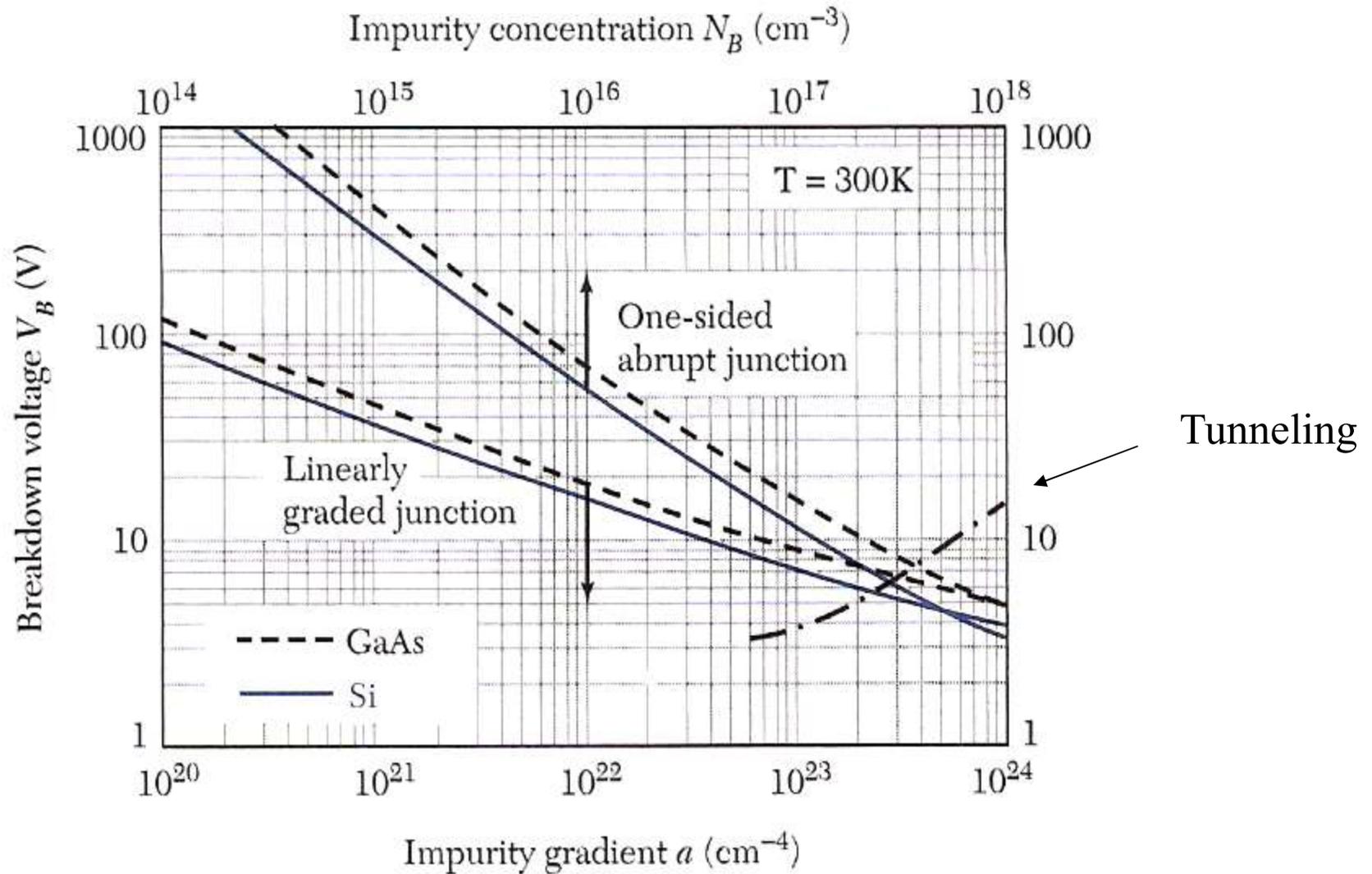
Occurs at low doping



Vertical: 5 mA/div

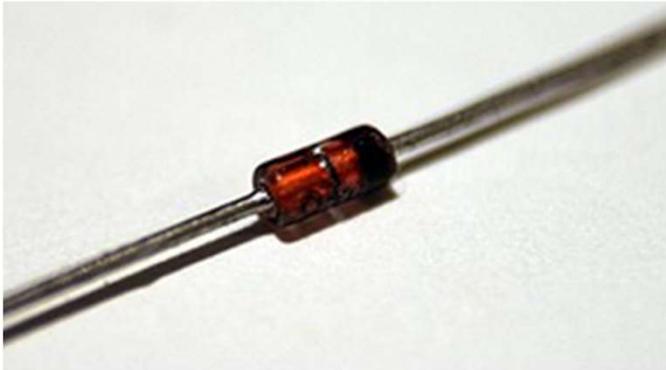
Horizontal: 5 V/div

# Avalanche breakdown

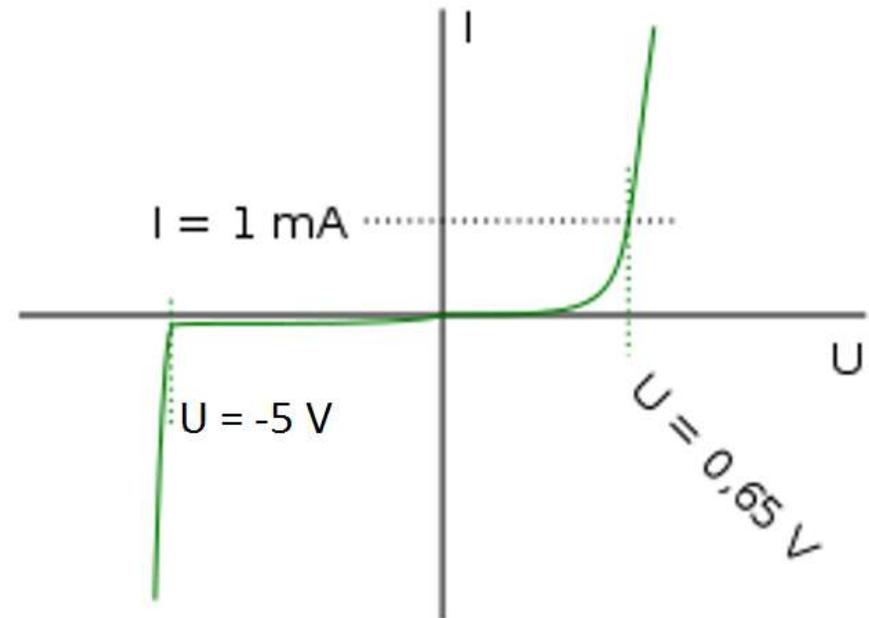


# Zener diodes

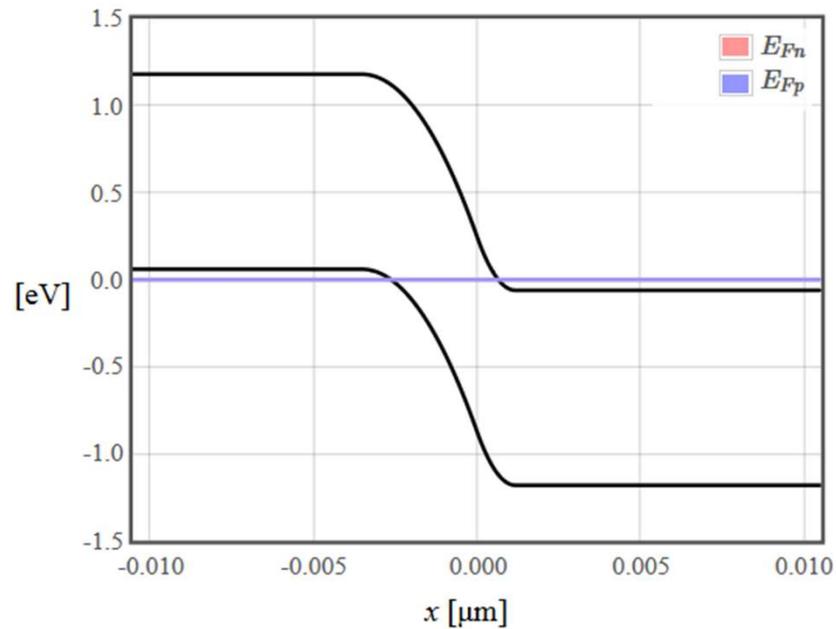
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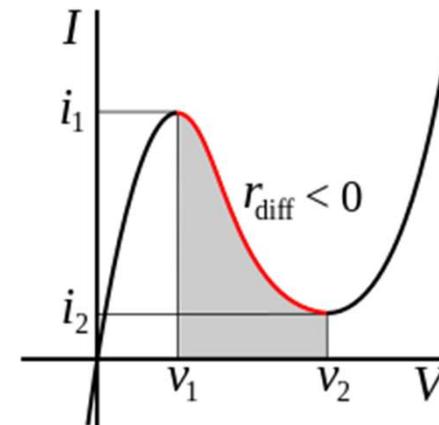
Zener tunneling and avalanche breakdown are present in a Zener diode. The combination is used to make the breakdown voltage temperature independent.



# Tunnel diodes / Esaki diodes



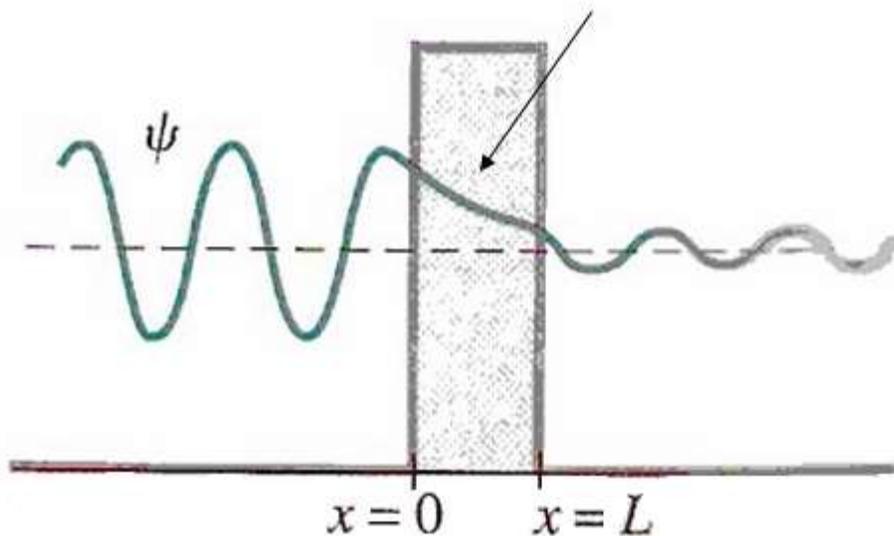
Both sides of the diode are degenerately doped



# Tunneling

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wave decays exponentially in the classically forbidden region



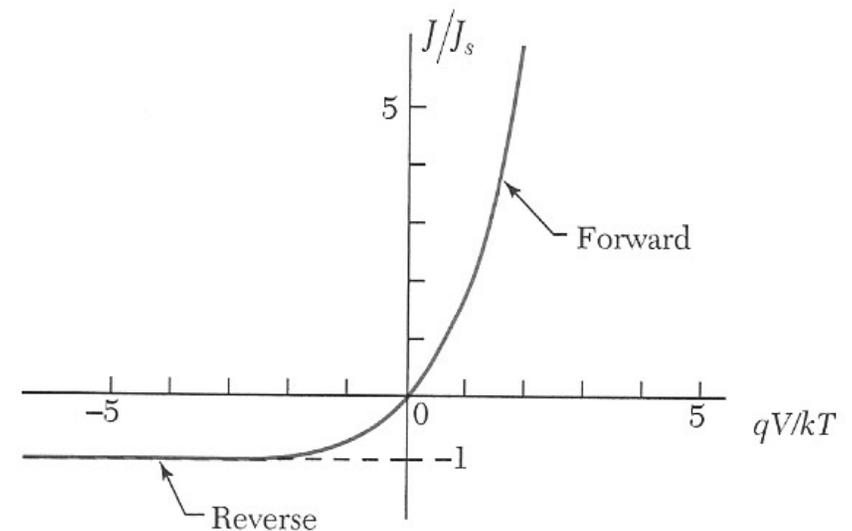
Tunneling is a wave phenomena. Tunneling and total internal reflection are used in a beam splitter.

# Metal-Semiconductor Contacts

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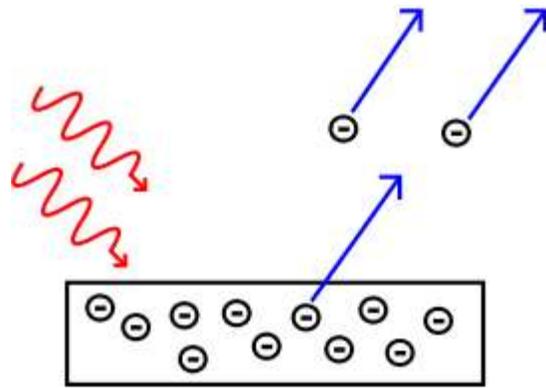
# metal - semiconductor contacts

Photoelectric effect  
 Schottky barriers  
 Schottky diodes  
 Ohmic contacts  
 Thermionic emission  
 Tunnel contacts

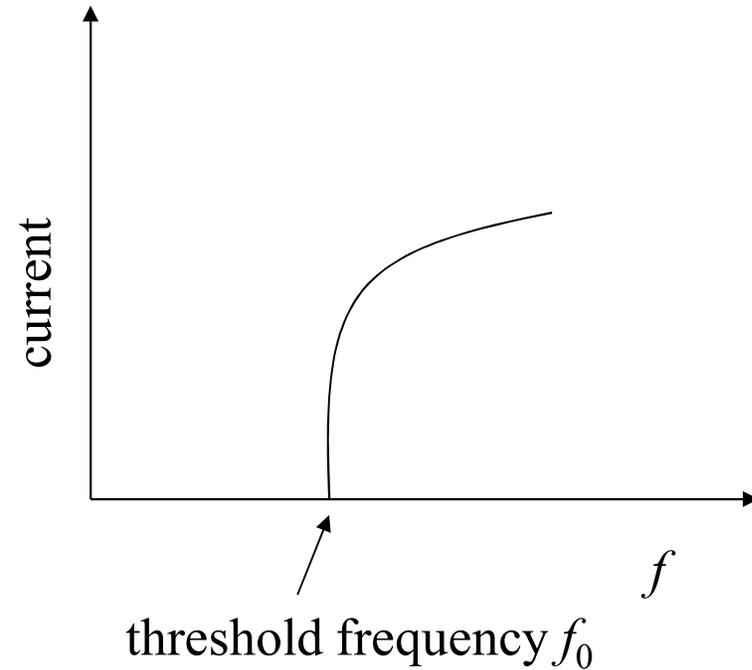


# Photoelectric effect

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$hf_0 = e\phi$  at threshold  
workfunction

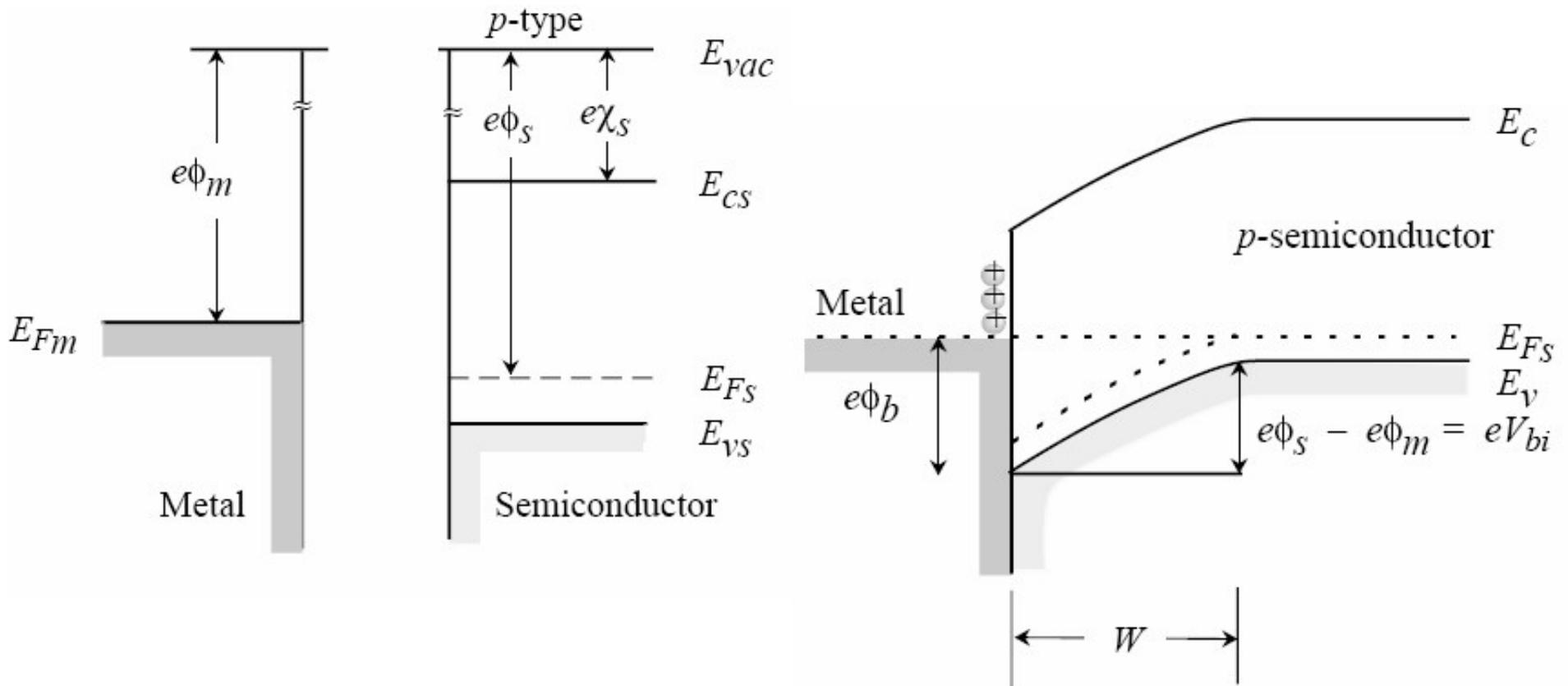


Work functions of some metals	
Element	Work function, $\phi_m$ (volt)
Ag, silver	4.26
Al, aluminum	4.28
Au, gold	5.1
Cr, chromium	4.5
Mo, molybdenum	4.6
Ni, nickel	5.15
Pd, palladium	5.12
Pt, platinum	5.65
Ti, titanium	4.33
W, tungsten	4.55

There is a dipole field at the surface of a metal. This electric field must be overcome for an electron to escape.

Singh

# work function - electron affinity



If  $\phi_s < \phi_m$ , the semiconductor bands bend down.

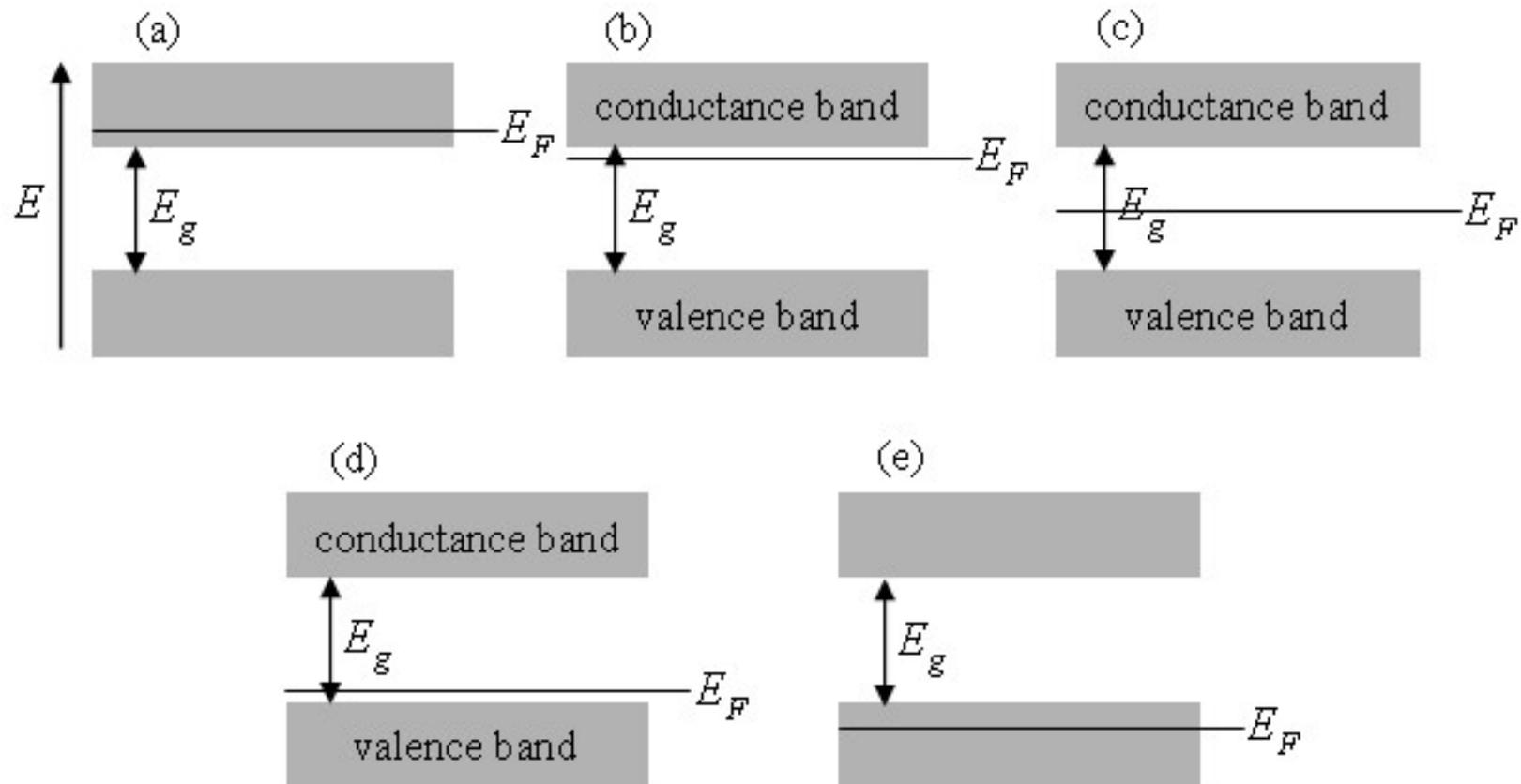
If  $\phi_s > \phi_m$ , the semiconductor bands bend up.

Work functions of some metals

Element	Work function, $\phi_m$ (volt)
Ag, silver	4.26
Al, aluminum	4.28
Au, gold	5.1
Cr, chromium	4.5
Mo, molybdenum	4.6
Ni, nickel	5.15
Pd, palladium	5.12
Pt, platinum	5.65
Ti, titanium	4.33
W, tungsten	4.55

Electron affinity of some semiconductors

Element	Electron affinity, $\chi$ (volt)
Ge, germanium	4.13
Si, silicon	4.01
GaAs, gallium arsenide	4.07
AlAs, aluminum arsenide	3.5



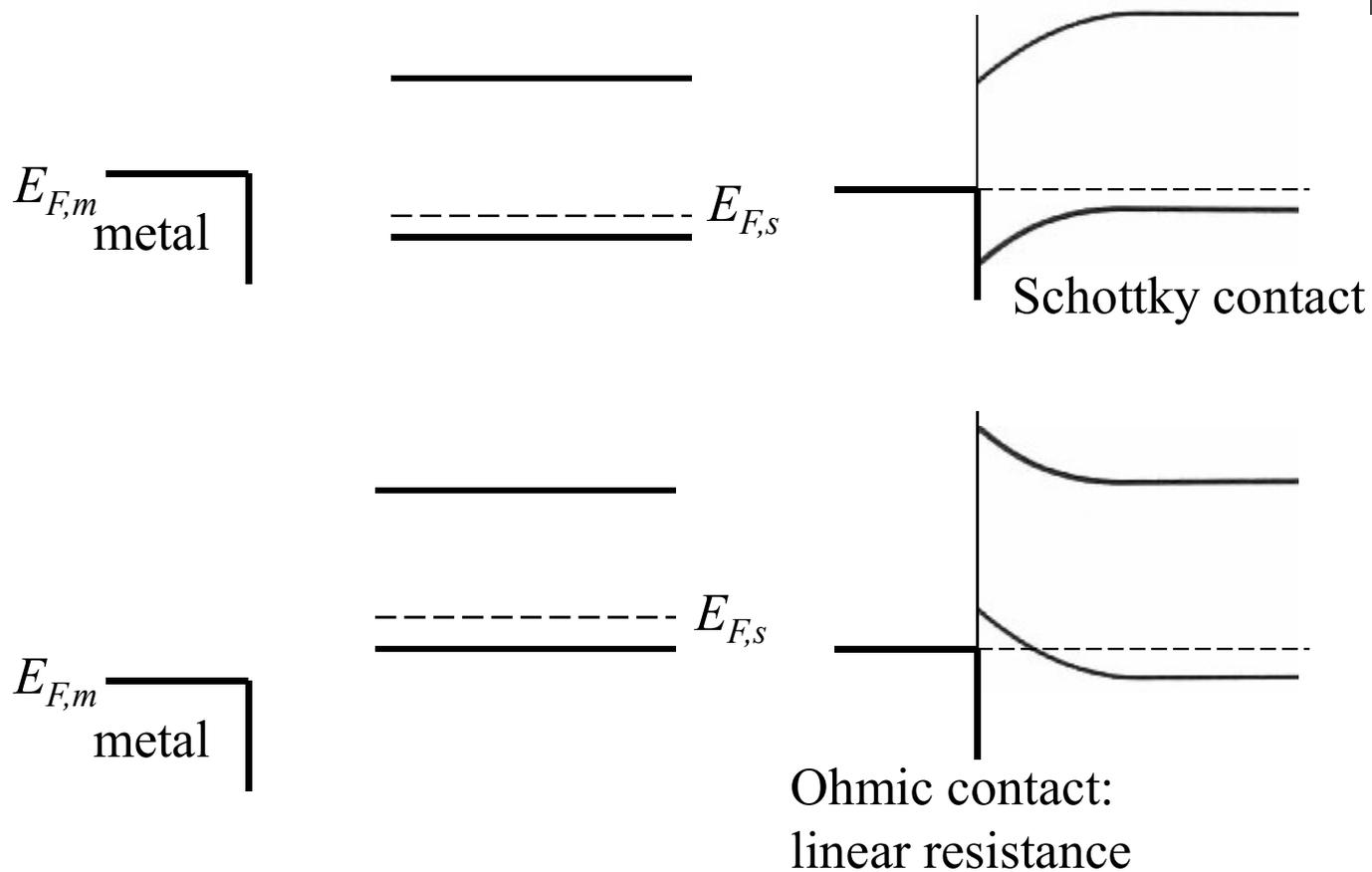
(a) A metal with a small workfunction. (b) An n-type semiconductor. (c) An insulator. (d) A p-type semiconductor. (e) A metal with a large workfunction.

p-type

Walter Schottky



# Schottky contact / ohmic contact



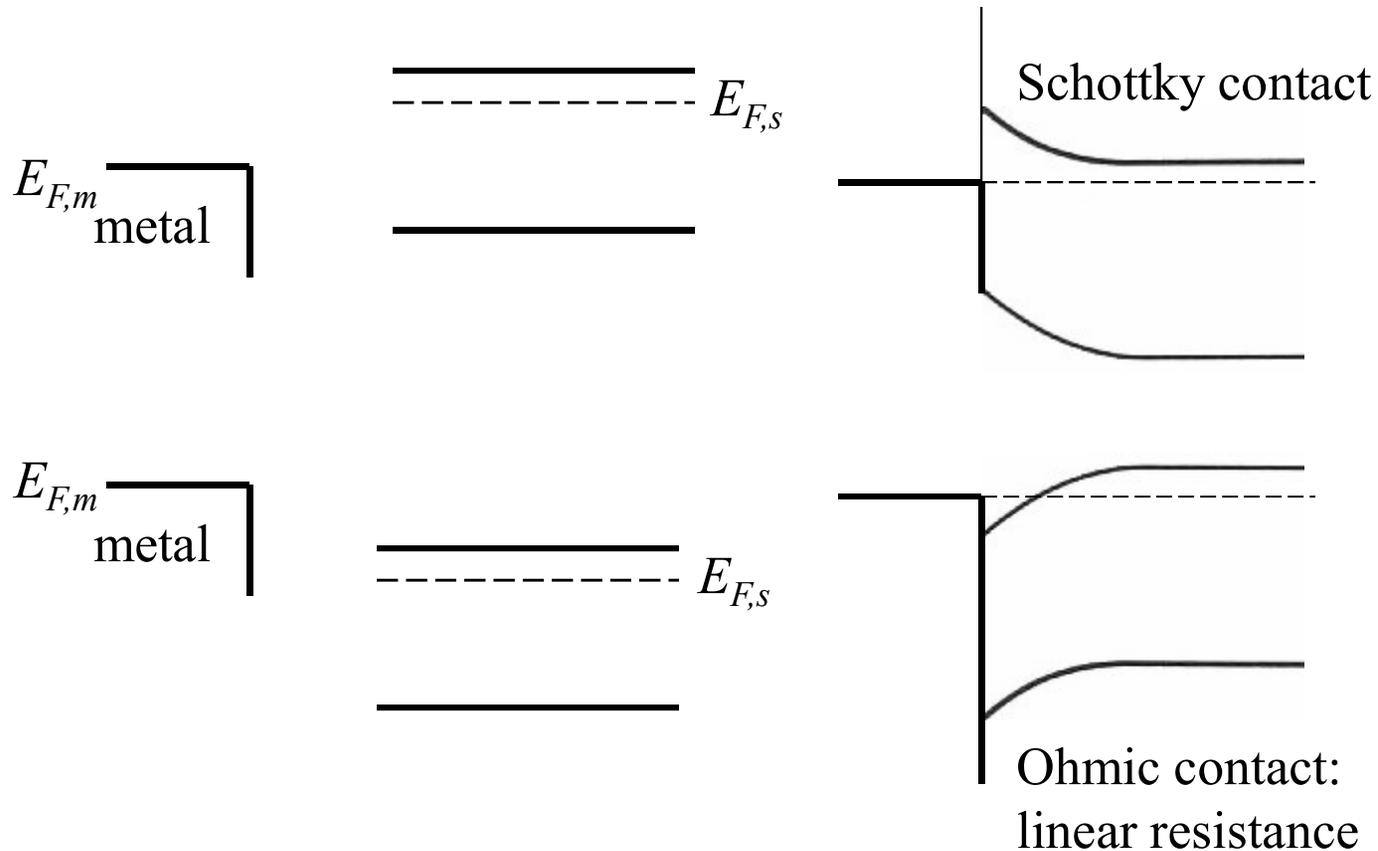
specific contact resistance:

$$R_c = \left( \frac{\partial J}{\partial V} \right)^{-1} \quad \Omega\text{-cm}^2$$

n-type

## Schottky contact / ohmic contact

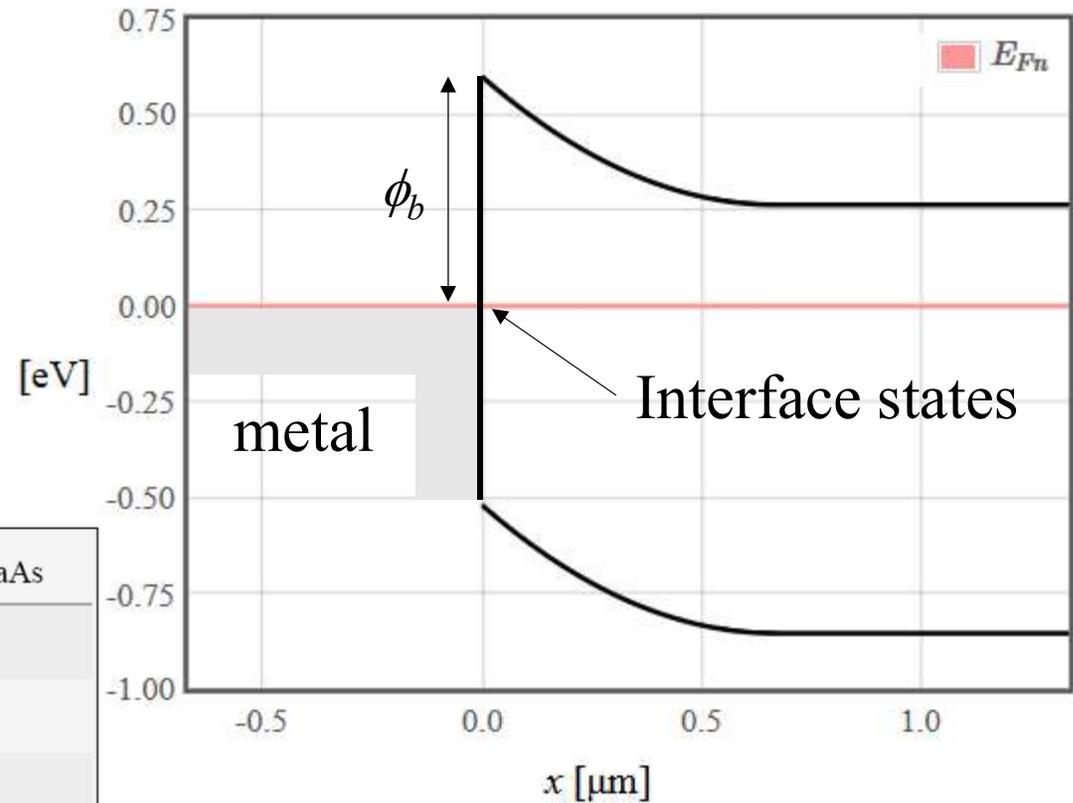
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specific contact resistance:  $R_c = \left( \frac{\partial J}{\partial V} \right)^{-1} \quad \Omega\text{-cm}^2$

# Interface states

SCHOTTKY METAL	<i>n</i> Si	<i>p</i> Si	<i>n</i> GaAs
Aluminum, Al	0.7	0.8	
Titanium, Ti	0.5	0.61	
Tungsten, W	0.67		
Gold, Au	0.79	0.25	0.9
Silver, Ag			0.88
Platinum, Pt			0.86
PtSi	0.85	0.2	
NiSi <sub>2</sub>	0.7	0.45	



**substance: silicon (Si)**

**property: Schottky barrier heights**

average experimental values are given, different data found in the literature scatter considerably.

Contact	Numerical value	Experimental conditions	Experimental method, remarks	
n-Si:Ag	0.56 eV	chemically etched	C-V and I-V characteristics	
p-Si:Ag	0.54 eV			
n-Si:Al	0.50 eV	n-Si:Pt	0.81 eV	
p-Si:Al	0.58 eV	n-Si:Sn	0.58 eV	
n-Si:Au	0.81 eV	n-Si:Ta	0.57 eV	
p-Si:Au	0.34 eV	n-Si:Ti	0.50 eV	
n-Si:Cr	0.59 eV	n-Si:W	0.65 eV	
n-Si:Cu	0.66 eV	n-Si:Ag	0.78 eV	
p-Si:Cu	0.46 eV	n-Si:Al	0.75 eV	
n-Si:Fe	0.65 eV	n-Si:Au	0.73 eV	cleaved, uhv
n-Si:Mg	0.55 eV	n-Si:Ca	0.40 eV	I-V and photoele
n-Si:Mo	0.57 eV	n-Si:Co	0.61 eV	C-V and I-V ch
n-Si:Ni	0.67 eV	n-Si:Cu	0.77 eV	I-V and photoel
p-Si:Ni	0.51 eV	n-Si:K	0.46 eV	
n-Si:Pb	0.41 eV	n-Si:Mg	0.46 eV	
p-Si:Pb	0.55 eV	n-Si:Na	0.43 eV	
n-Si:Pd	0.72 eV	n-Si:Ni	0.59 eV	
		n-Si:Pb	0.61 eV	
		n-Si:Pt	0.81 eV	
		n-Si:Pt	0.74 eV	

[http://www.springermaterials.com/navigation/#n\\_240905\\_Silicon+%2528Si%2529](http://www.springermaterials.com/navigation/#n_240905_Silicon+%2528Si%2529)

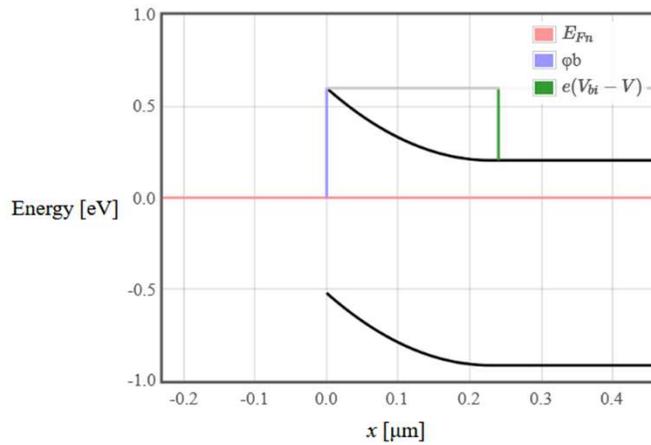
# Schottky barrier

$\phi_b = 0.6$  eV  
 $E_g = 1.166 - 4.73E-4 * T * T / (T + 636)$  eV  
 $N_D = 1E15$  1/cm<sup>3</sup>  
 $N_c(300) = 2.78E19$  1/cm<sup>3</sup>  
 $T = 300$  K  
 $\epsilon_r = 12$   
 $V = -0.5$  V

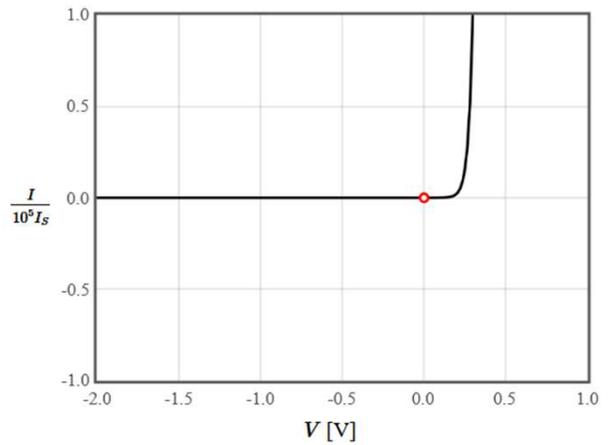
$E_g = 1.12$  eV     $W = 1.05$   $\mu\text{m}$      $V_{bi} = 0.335$  V     $C_j = 10.1$  nF/cm<sup>2</sup>

$$E = \frac{eN_D}{\epsilon_r \epsilon_0} (x - x_n)$$

Band diagram

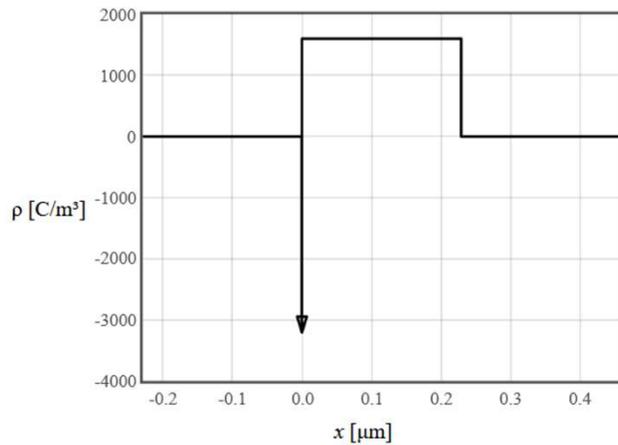


Current-Voltage Characteristics

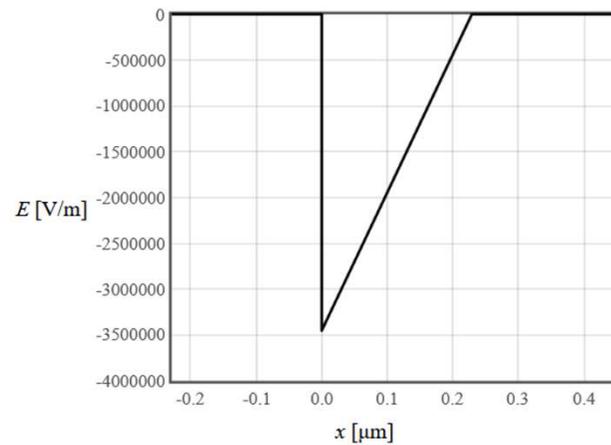


$$W \approx x_n = \sqrt{\frac{2\epsilon(V_{bi} - V)}{eN_D}}$$

Charge density



Electric field



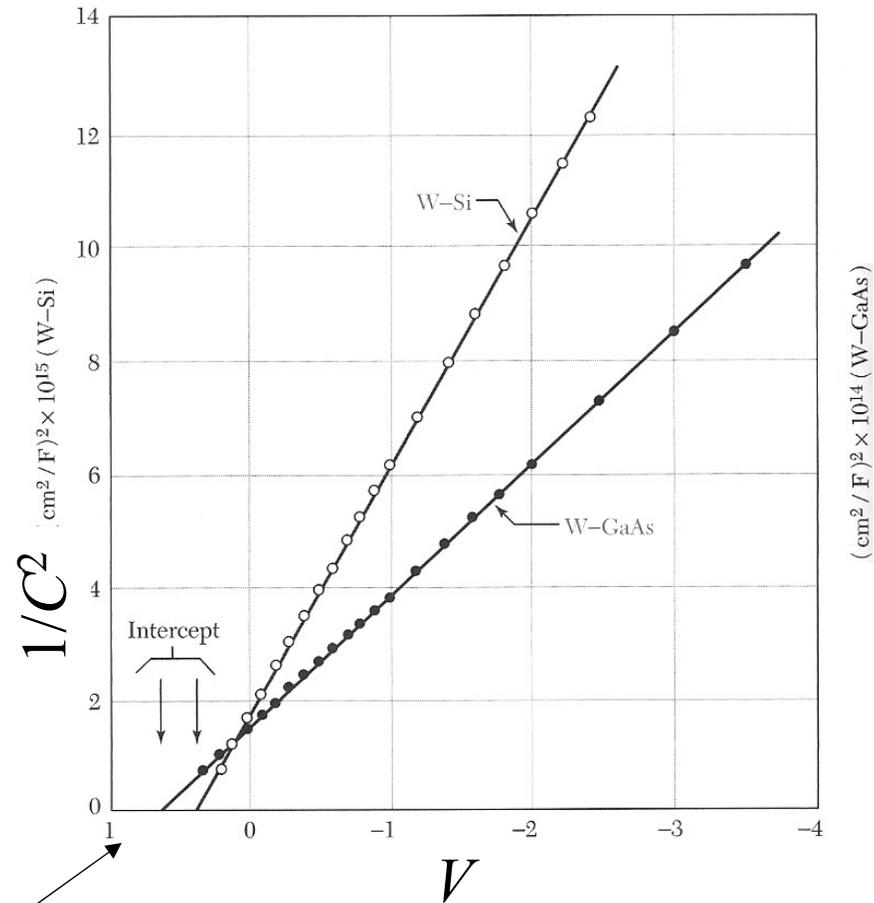
$$V = \frac{-eN_D}{\epsilon} \left( \frac{x^2}{2} - xx_n \right)$$

# CV measurements

$$x_p = \sqrt{\frac{2\epsilon(V_{bi} - V)}{eN_A}}$$

$$C = \frac{\epsilon}{x_p} = \sqrt{\frac{e\epsilon N_A}{2(V_{bi} - V)}} \quad \text{F m}^{-2}$$

$$\frac{1}{C^2} = \frac{2(V_{bi} - V)}{e\epsilon N_A}$$



GaAs has larger  $E_g$  and  $V_{bi}$

$$eV_{bi} = \phi_b - k_B T \ln \left( \frac{N_v(T)}{N_A} \right)$$

# Thermionic emission

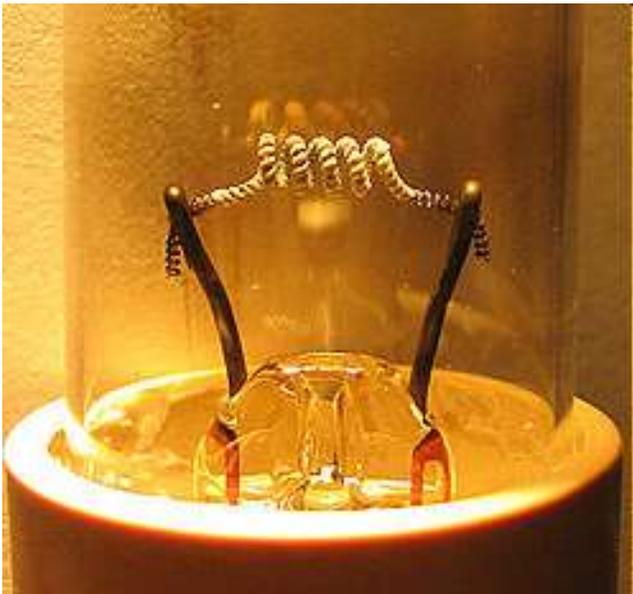
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1901 Richardson

Owen Willans Richardson

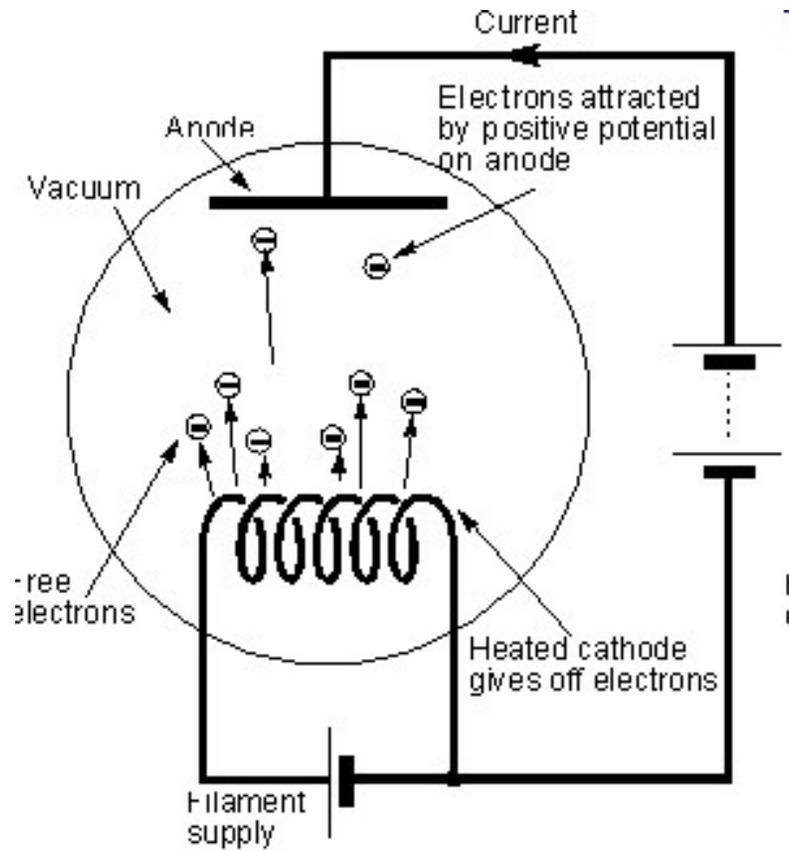
Current from a heated wire is:



$$I = \frac{Aem^*k_B^2}{2\pi^2\hbar^3} T^2 \exp\left(-\frac{\phi_b}{k_B T}\right) \left(\exp\left(\frac{eV}{k_B T}\right) - 1\right)$$

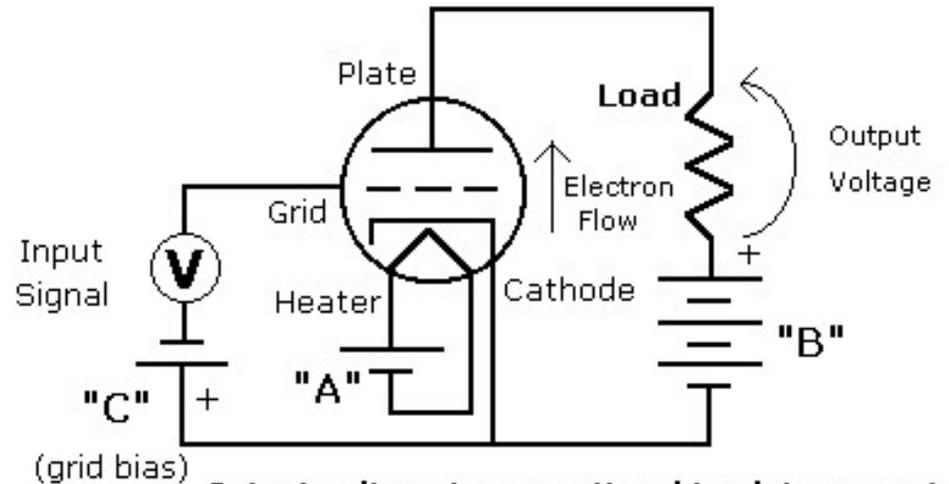
Some electrons have a thermal energy that exceeds the work function and escape from the wire.

# Vacuum diodes



diode

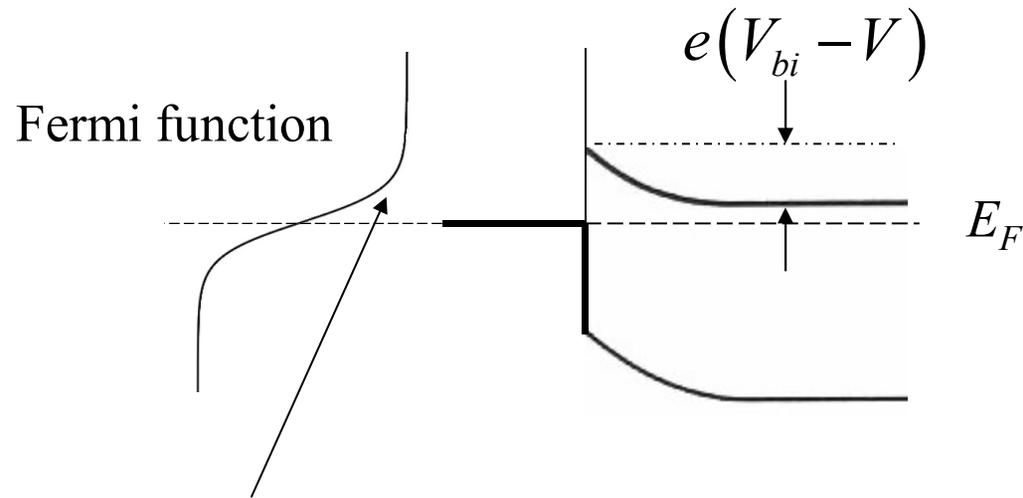
## The Common-cathode Triode Amplifier



**Output voltage is proportional to plate current, which is controlled by grid voltage.**



# Thermionic emission



$$f(E) \approx \exp\left(\frac{E_F - E}{k_B T}\right) = \exp\left(\frac{E_F}{k_B T}\right) \exp\left(\frac{-E}{k_B T}\right) \propto \exp\left(\frac{-E}{k_B T}\right)$$

The density of electrons with enough energy to go over the barriers  $\propto \exp\left(\frac{-E}{k_B T}\right)$

$$n_{th} \propto \exp\left(\frac{-E}{k_B T}\right) = \exp\left(\frac{-e(V_{bi} - V)}{k_B T}\right) = \exp\left(\frac{-eV_{bi}}{k_B T}\right) \exp\left(\frac{eV}{k_B T}\right)$$

# Thermionic emission

$$n_{th} \propto \exp\left(\frac{eV}{k_B T}\right)$$

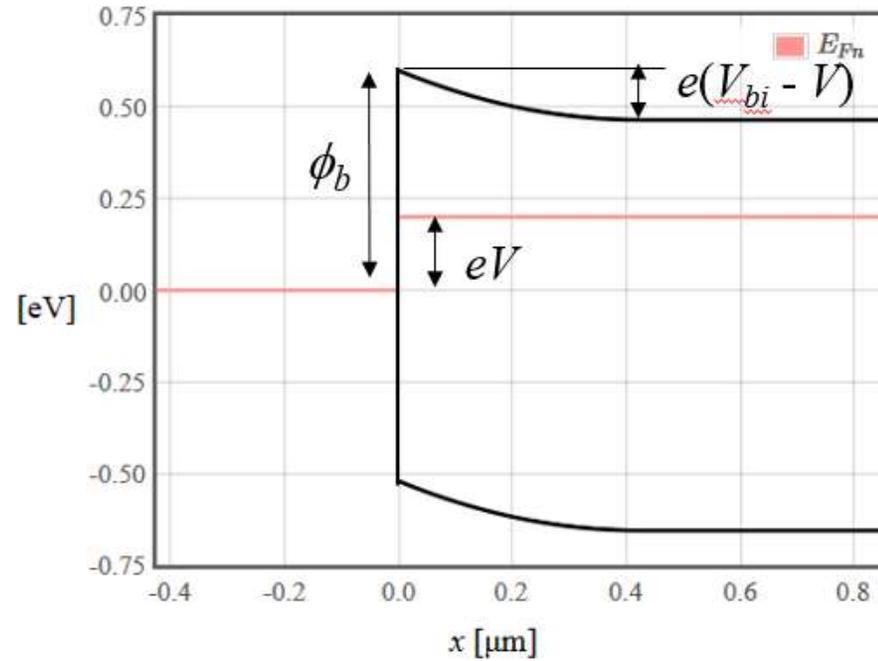
$$I_{sm} \propto n_{th} \propto \exp\left(\frac{eV}{k_B T}\right)$$

$$I_{ms} = I_{sm}(V = 0)$$

$$I = I_{sm} + I_{ms} = I_{ms}(T) \left( \exp\left(\frac{eV}{k_B T}\right) - 1 \right)$$

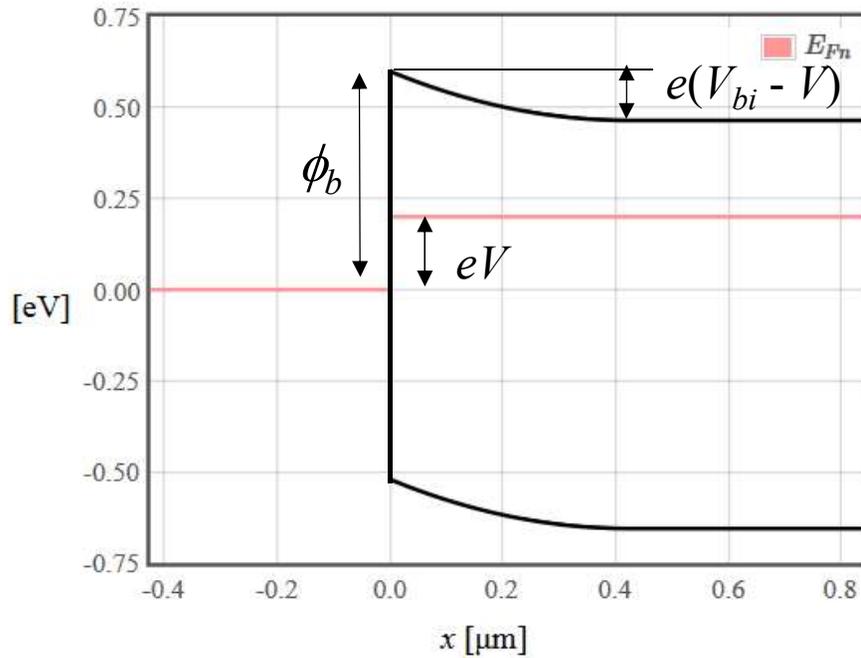
$$I = \frac{Aem^*k_B^2}{2\pi^2\hbar^3} T^2 \exp\left(-\frac{\phi_b}{k_B T}\right) \left( \exp\left(\frac{eV}{k_B T}\right) - 1 \right)$$

Forward bias



# Schottky barrier

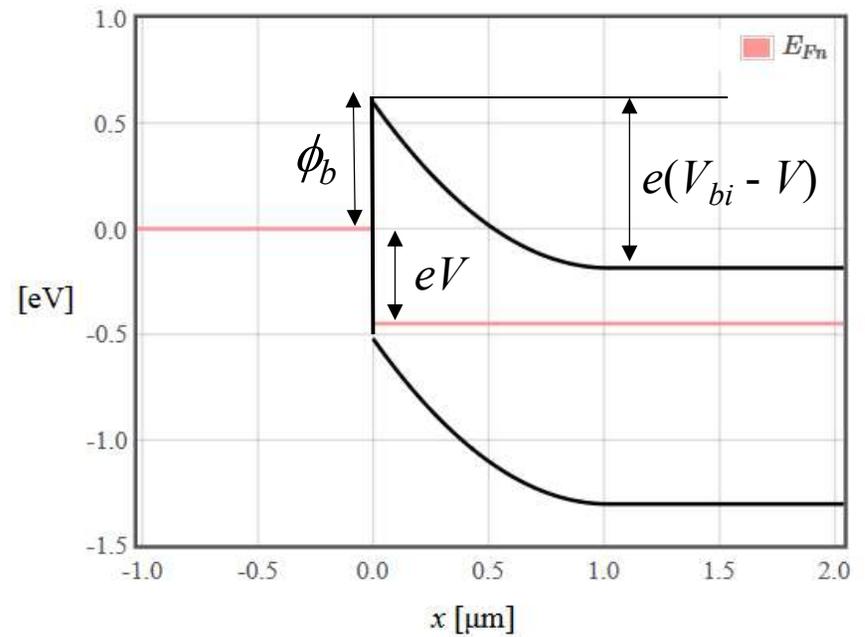
Forward bias



$$I_{sm} \sim \exp(eV/k_B T)$$

$$I_{ms} \text{ constant}$$

Reverse bias



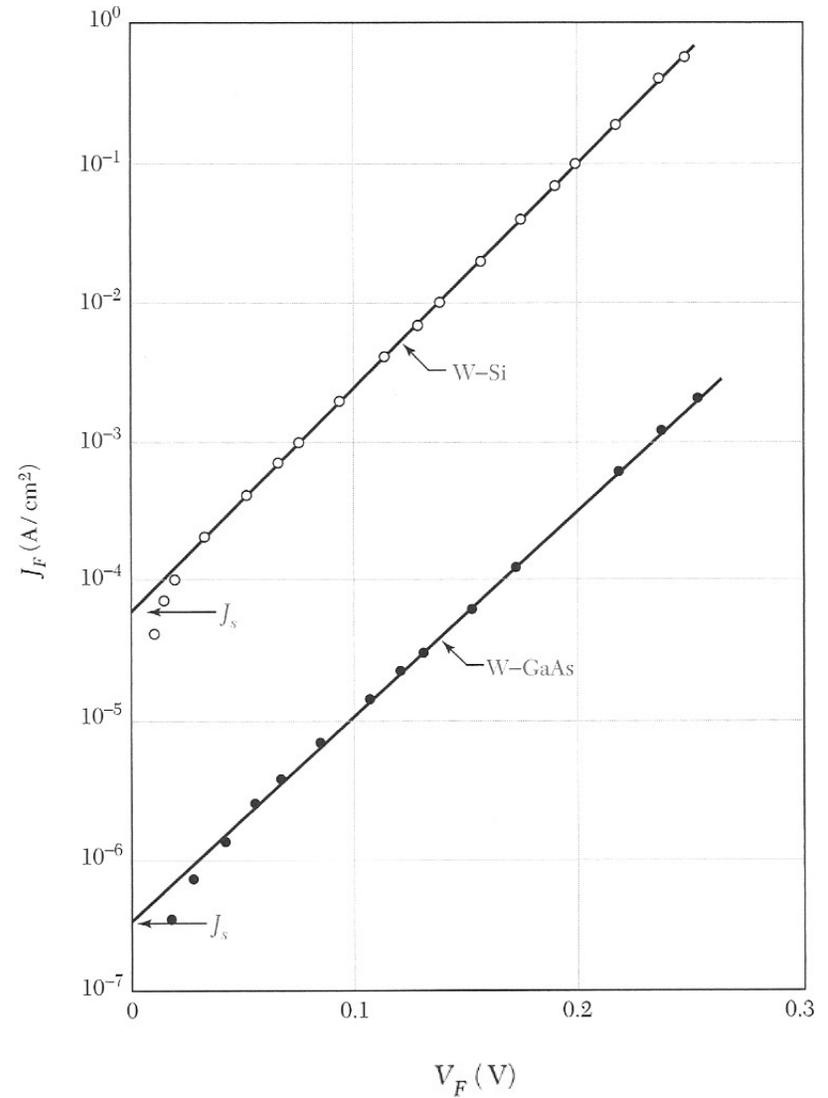
$$I_{sm} \sim 0$$

$$I_{ms} \text{ constant}$$

# Thermionic emission

$$I = I_{sm} + I_{ms} = I_s \left( e^{\frac{eV}{k_B T}} - 1 \right)$$

Nonideality factor = 1



# Schottky diodes

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Majority carrier current dominates.

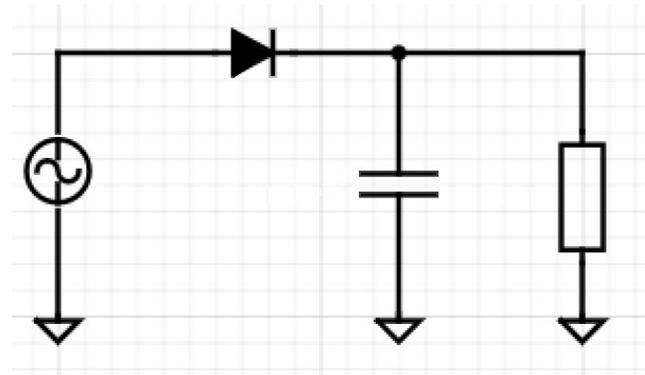
nonideality factor  $\sim 1$ .

Fast response, no recombination of electron-hole pairs required.

Used as rf mixers.

Low turn on voltage - high saturation current

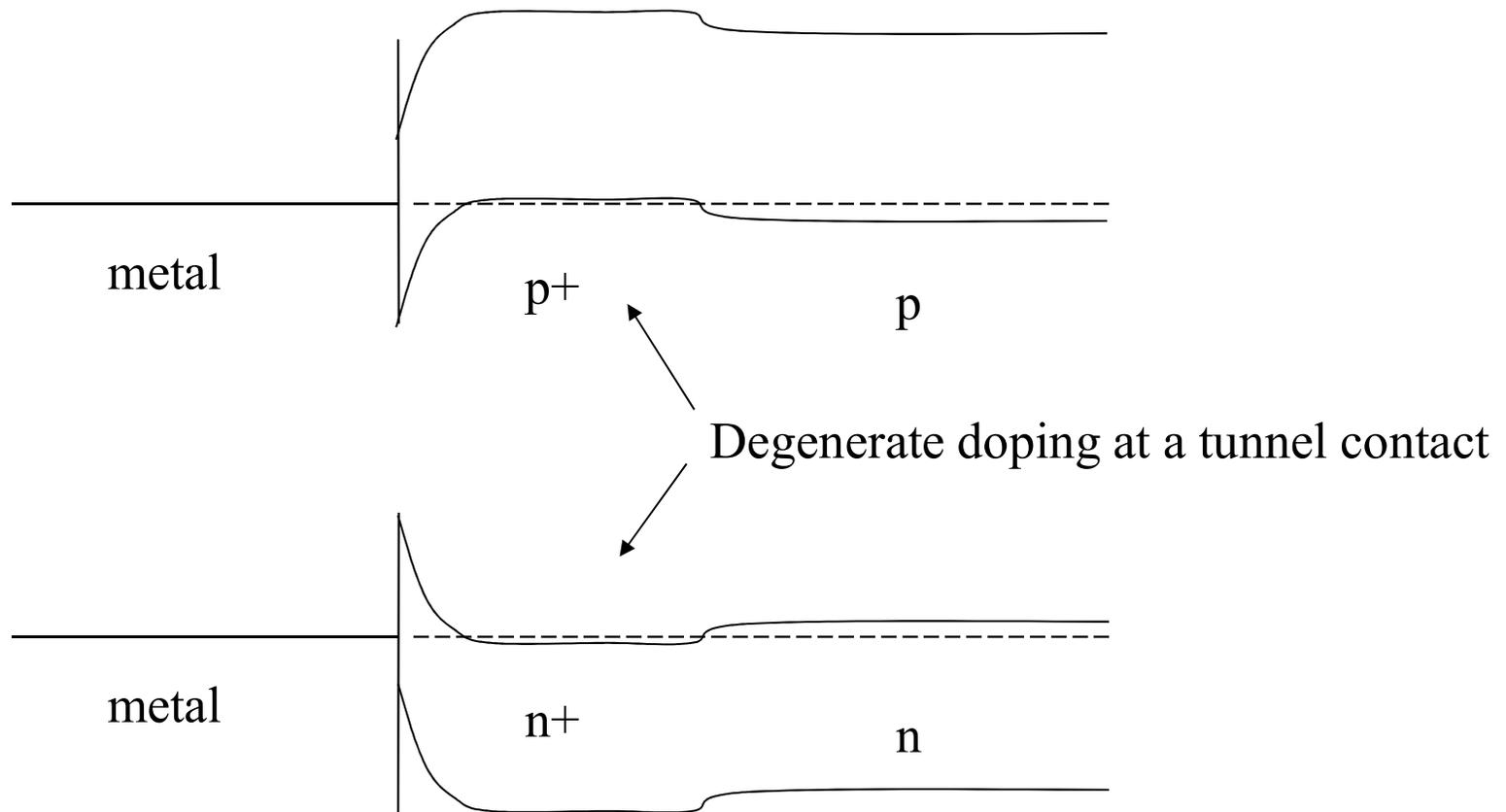
$$I = I_s \left( e^{\frac{eV}{k_B T}} - 1 \right)$$



# Tunnel contacts

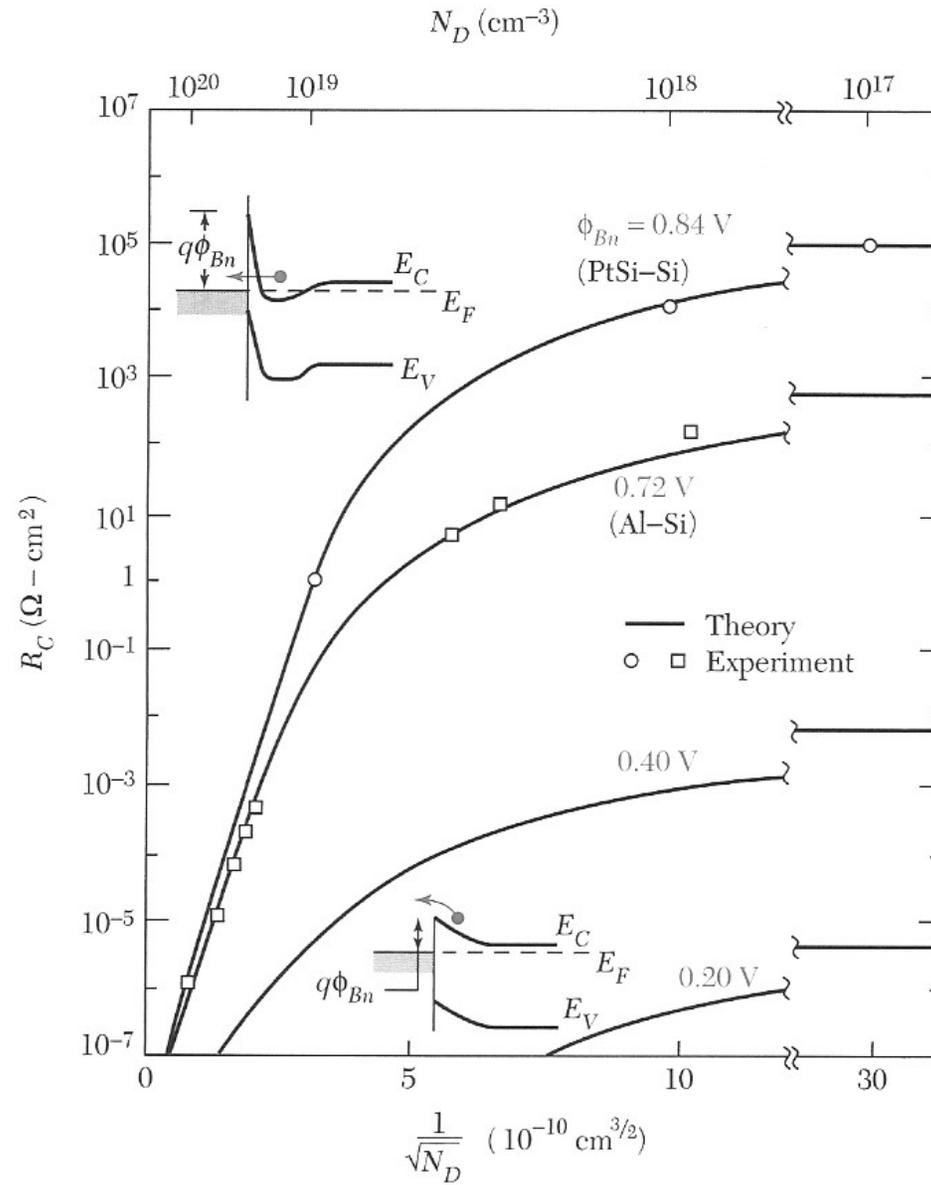
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For high doping, the Schottky barrier is so thin that electrons can tunnel through it.



Tunnel contacts have a linear resistance.

# Contacts



# Transport mechanisms

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Drift

Diffusion

Thermionic emission

Tunneling

All mechanisms are always present.

One or two transport mechanisms can dominate depending on the device and the bias conditions.

In a forward biased pn-junction, diffusion dominates.

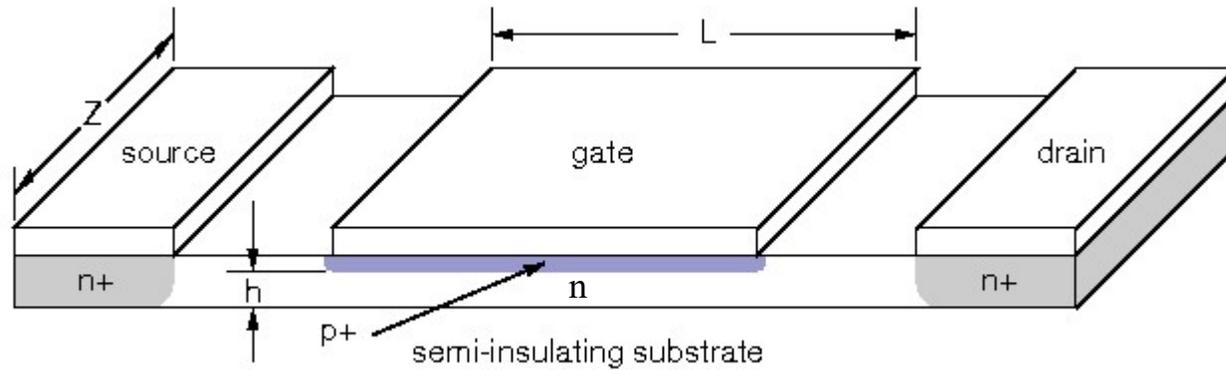
In a tunnel contact, tunneling dominates.

In a Schottky diode, thermionic emission dominates.

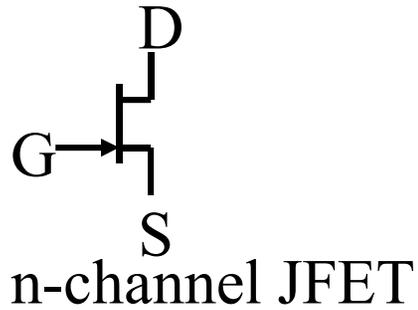
# Junction Field Effect Transistors (JFETs)

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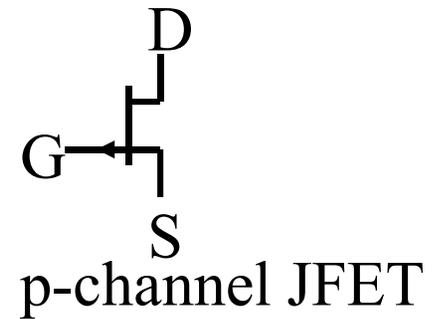
# JFET



n-channel JFET



$$x_n = \sqrt{\frac{2\epsilon(V_{bi} - V)}{eN_D}}$$



Pinch-off at  $h = x_n$

At Pinch-off, 
$$V = V_{bi} - \frac{eN_D h^2}{2\epsilon}$$

$$V_p = \frac{eN_D h^2}{2\epsilon}$$